



Properties of a new series of Hamamatsu Si diodes

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A new series of diodes FZ-Si (Hamamatsu) investigated by:

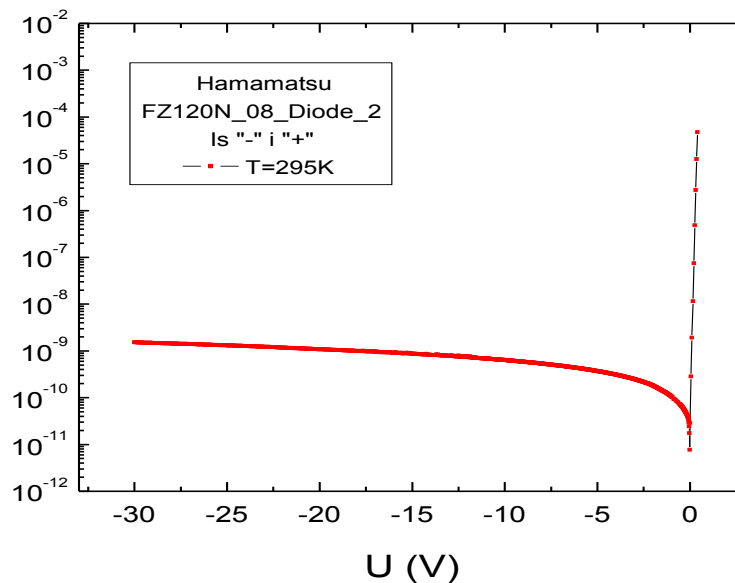
- 1) a standard technique (I(V) and C(V));
- 2) by microwave photoconductivity decay measurement;
- 3) the response on the linear front bias pulse technique (BELIV);
- 4) the photoconductivity spectra in the extrinsic region.

Measurements performed at room at a low temperature.

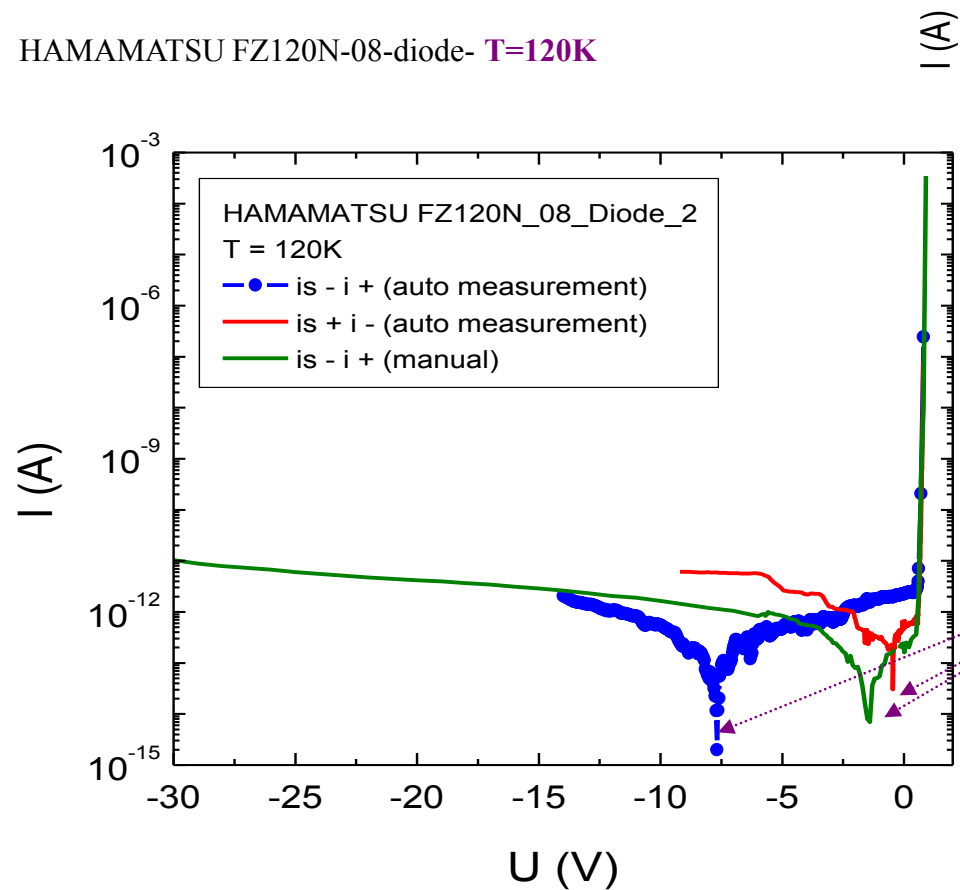
The results are compared with the similar measurements in other supplier and in irradiated samples.

I-V characteristics in non-irradiated diode

HAMAMATSU FZ120N-08-diode- **T=295 K**



HAMAMATSU FZ120N-08-diode- **T=120K**



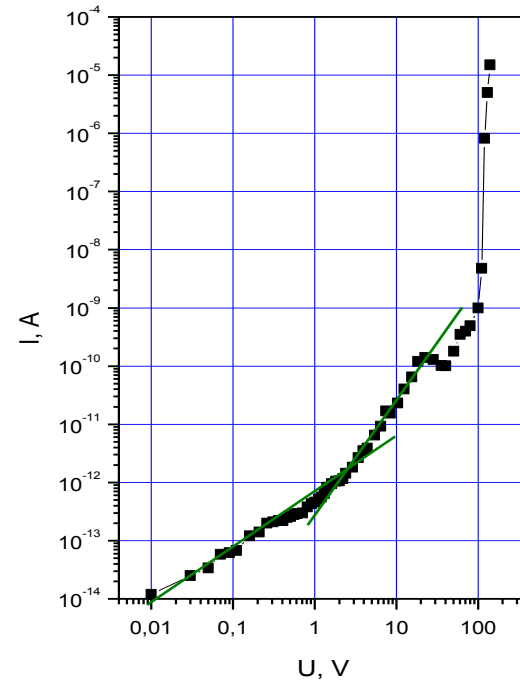
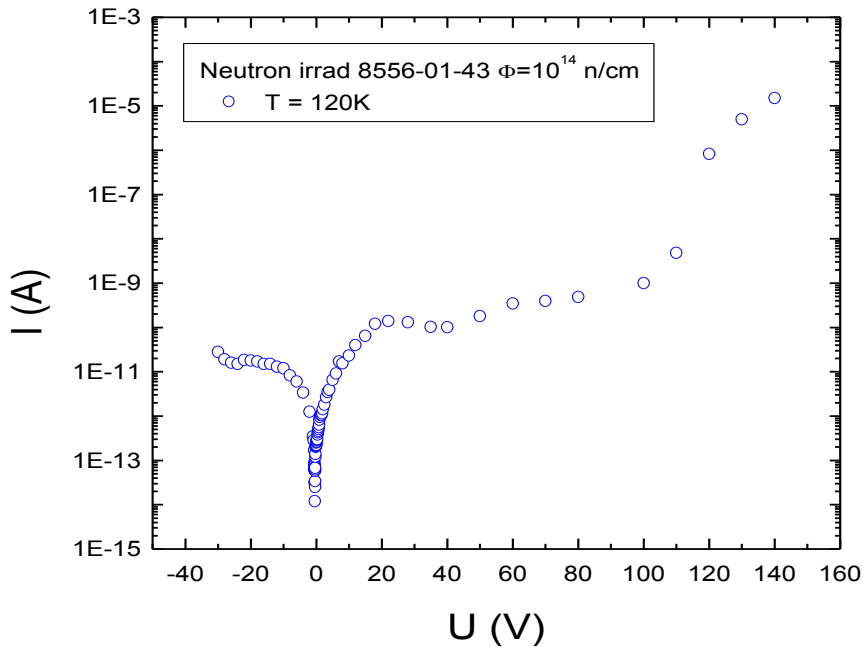
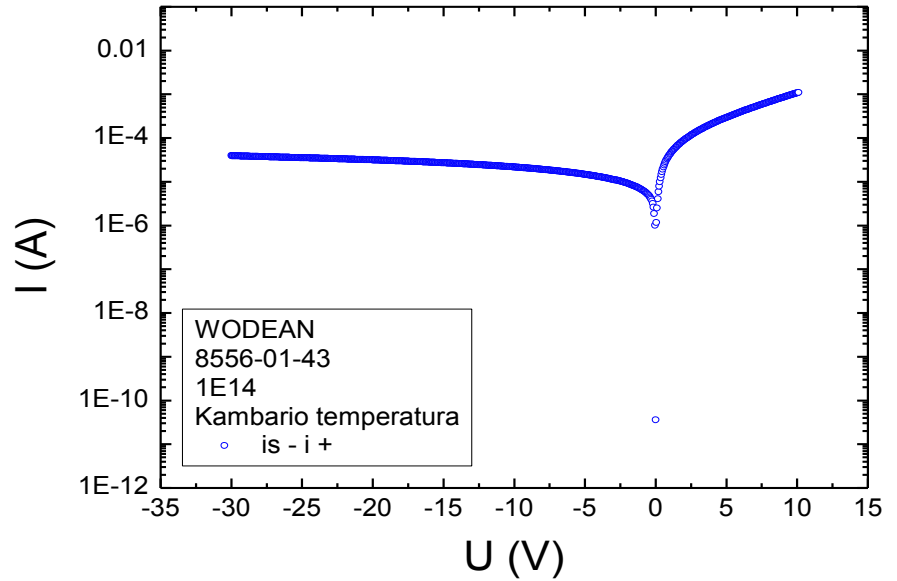
Surface charge on high resistivity/isolator ???
(non-metallized) material with very long (10^3 s) relaxation

I-V characteristics in radiation damaged diode

WODEAN 8556-01-43 MCZ Si
 neutrons 1014 cm⁻² diode **T= 295 K**
still diode –like characteristic

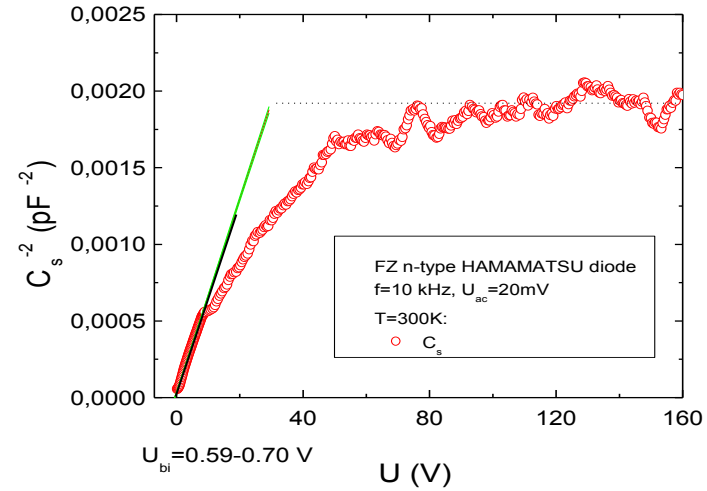
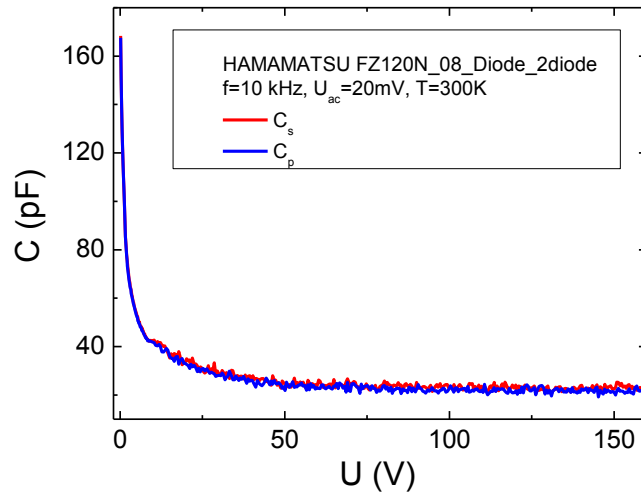
T= 120K

WODEAN 8556-01-43 MCZ Si neutrons
 1014 cm⁻² **diode-?**
Insulator like characteristic

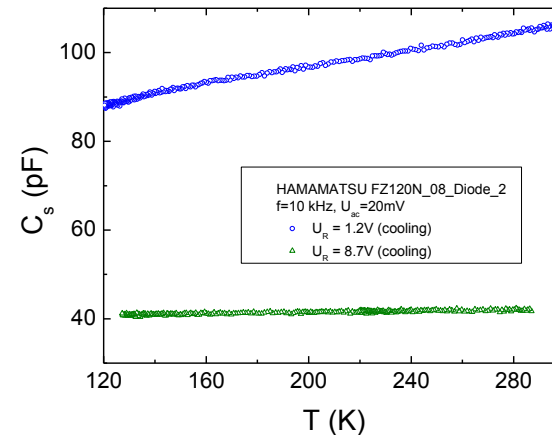
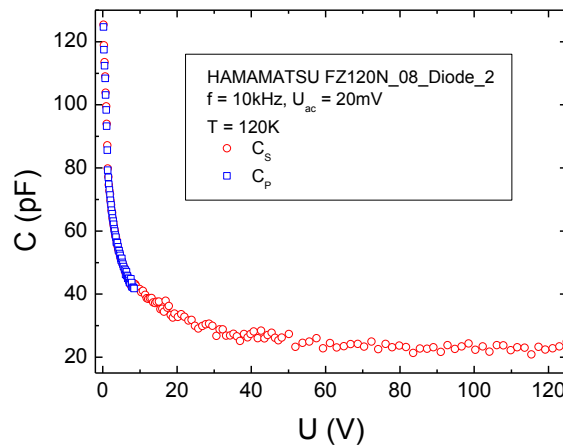


C-V-T characteristics in non-irradiated diode

Non-irradiated Hamamatsu diode T=300K

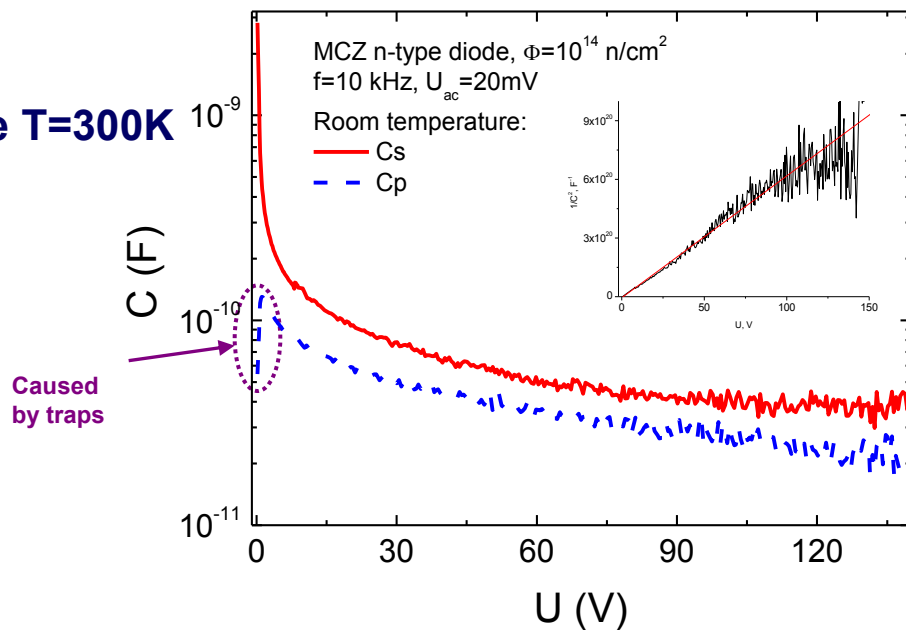


Non-irradiated Hamamatsu diode T=120K (diode barrier exists over all the range of T)

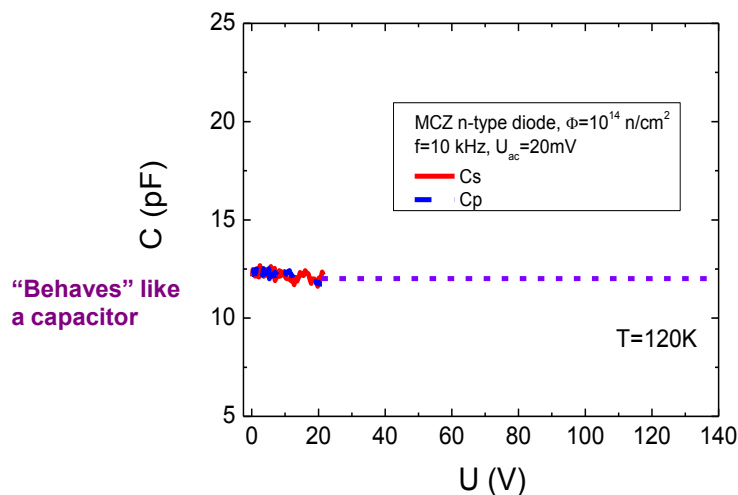
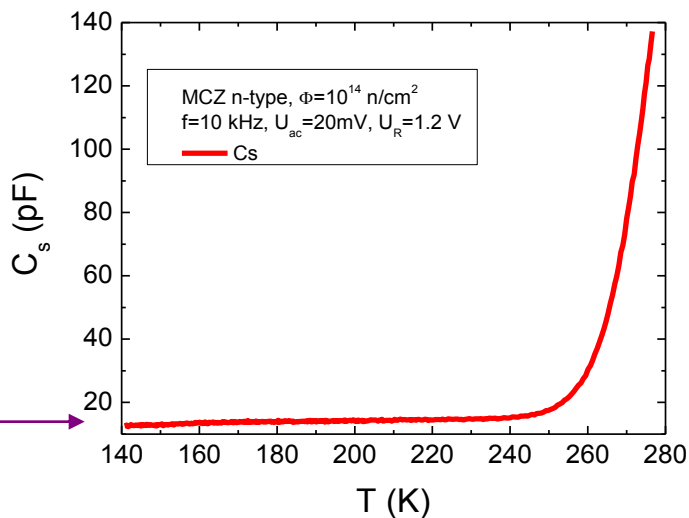


C-V-T characteristics in radiation damaged diode

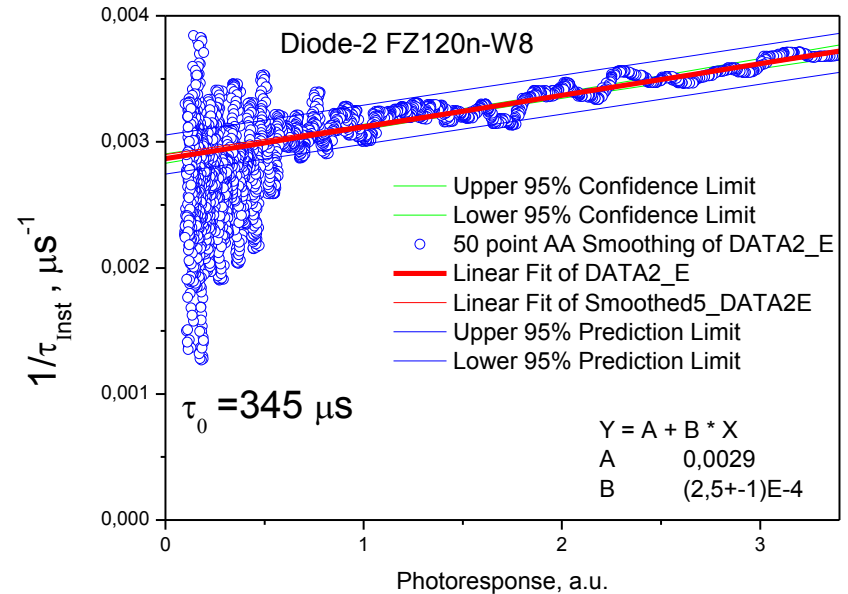
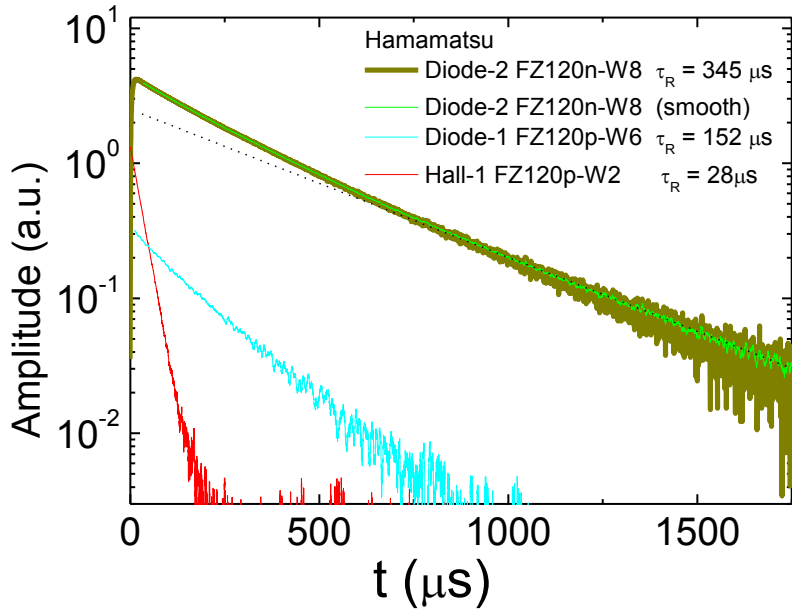
Neutron-irradiated 10^{14} cm^{-2} MCZ diode $T=300\text{K}$



Neutron-irradiated 10^{14} cm^{-2} MCZ diode $T=120\text{K}$



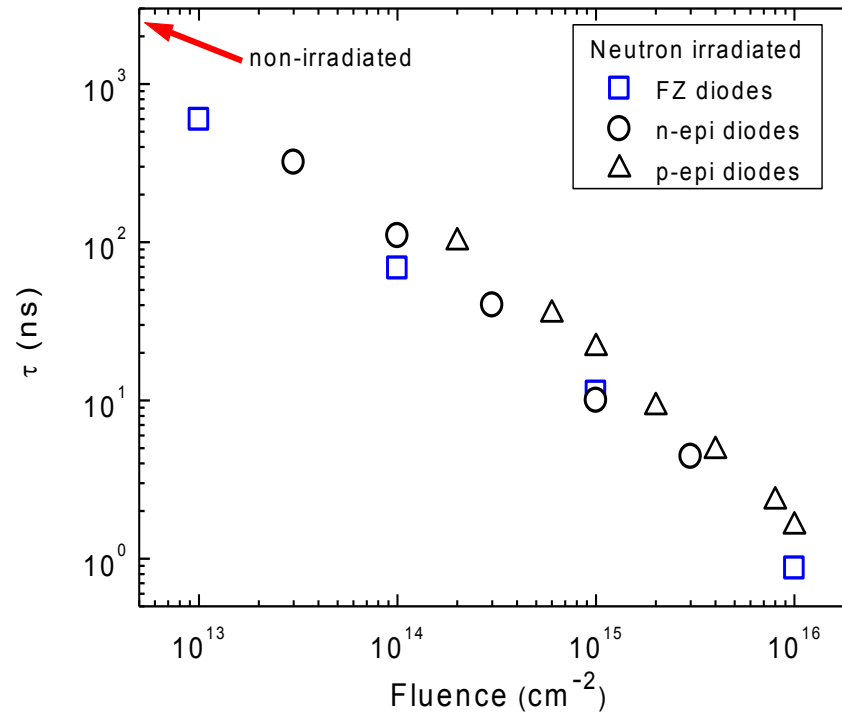
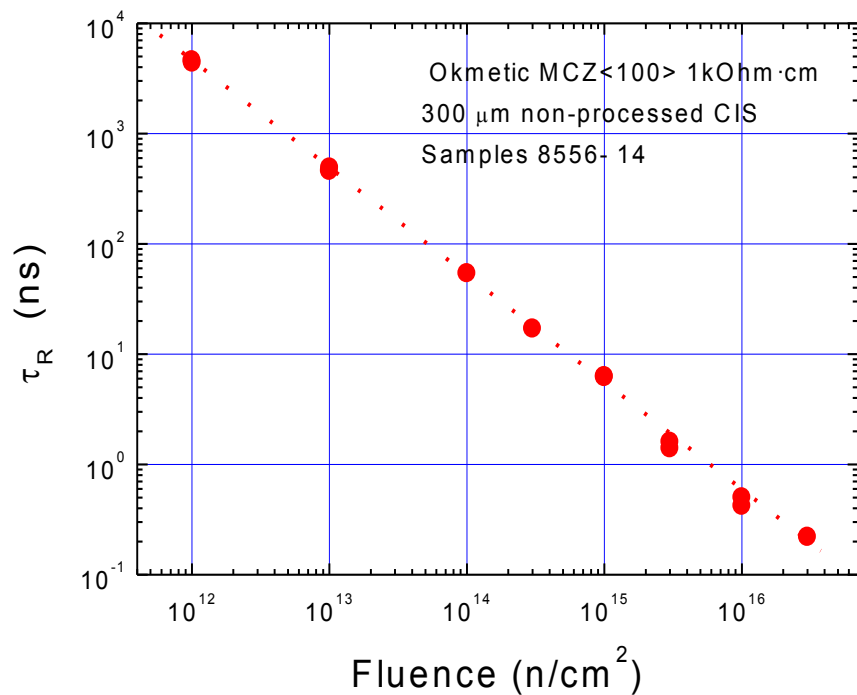
Carrier recombination characteristics in the non-irradiated CMS CEC samples



Carrier lifetime and MW-PCD transients at bulk ($\lambda_{ex} = 1062 \text{ nm}$) excitation (n- and p-type base diodes and “Hall” samples). $\Delta n = 1.5e12 \text{ cm}^{-3}$ ($S = \sim 2.5 e-16 \text{ cm}^2$)

Conclusion: Recombination centers in n-diode base are near to filled up;
 Recombination centers in p-diode base and in Hall sample are near to empty;

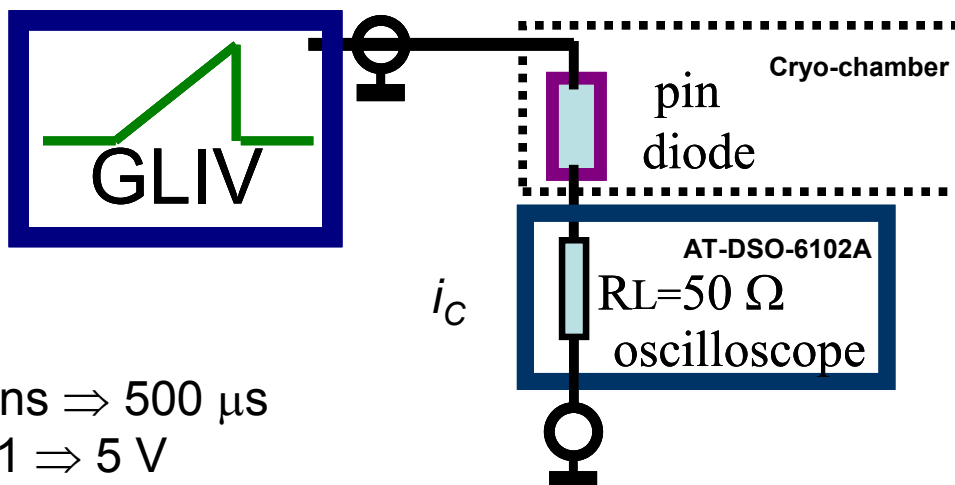
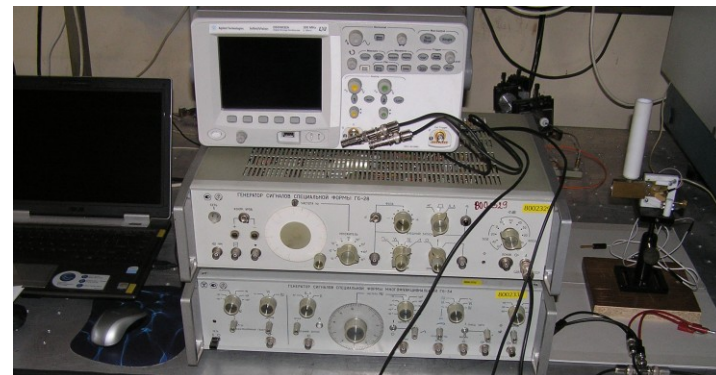
Neutron fluence dependent recombination lifetime in MCZ and epi- Si



BELIV technique

$$U(t) = U_p / \tau_{PL} t = At$$

$$\text{LIV ramp } A = U_p / \tau_{PL} = \partial U / \partial t$$



$$\tau_{PL} = 10 \text{ ns} \Rightarrow 500 \text{ } \mu\text{s}$$

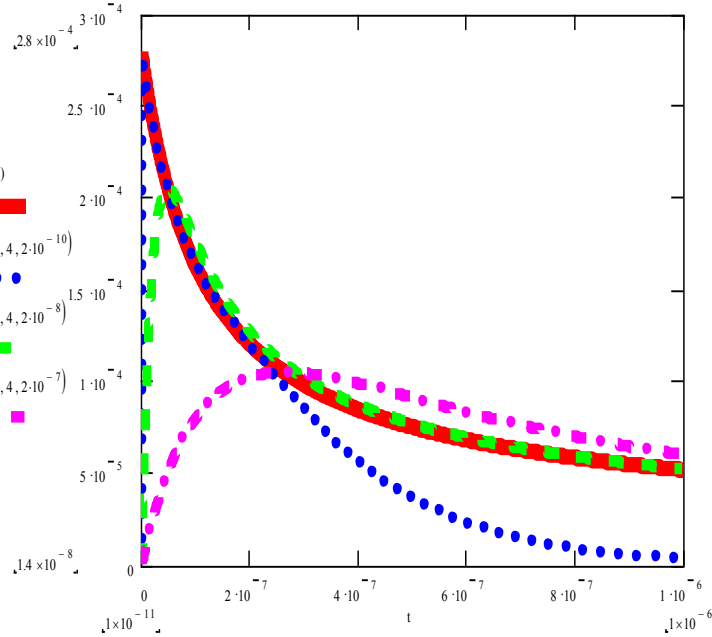
$$U_p = 0.01 \Rightarrow 5 \text{ V}$$

This method allows to avoid the displacement current change in time



BELIV model and simulations

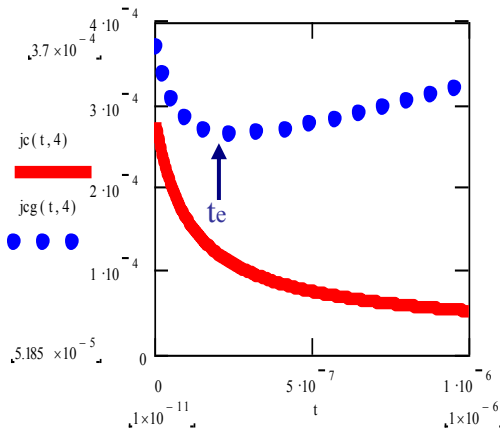
Reverse bias



$$i_C(t) = \frac{dq}{dt} = \frac{\partial U}{\partial t} \left(C_b + U \frac{\partial C_b}{\partial U} \right) = AC_{b0} \frac{1 + \frac{At}{2U_{bi}}}{\left(1 + \frac{At}{U_{bi}}\right)^{3/2}}$$

$$i_{CM}(t) = \frac{1}{\tau_{RC}} \int_0^t i_C(x) \exp\left[-\frac{(t-x)}{\tau_{RC}}\right] dx$$

Short transient processes acting in series due to t_D , τ_{DR} , τ_{capt} , τ_{gen} , etc (to complete a circuit) determine a delay & a reduction of the initial displacement current step. Similar effect perturbs the C-V characteristic at $U_R \rightarrow 0$ measured by impedance technique (LRC-meters).

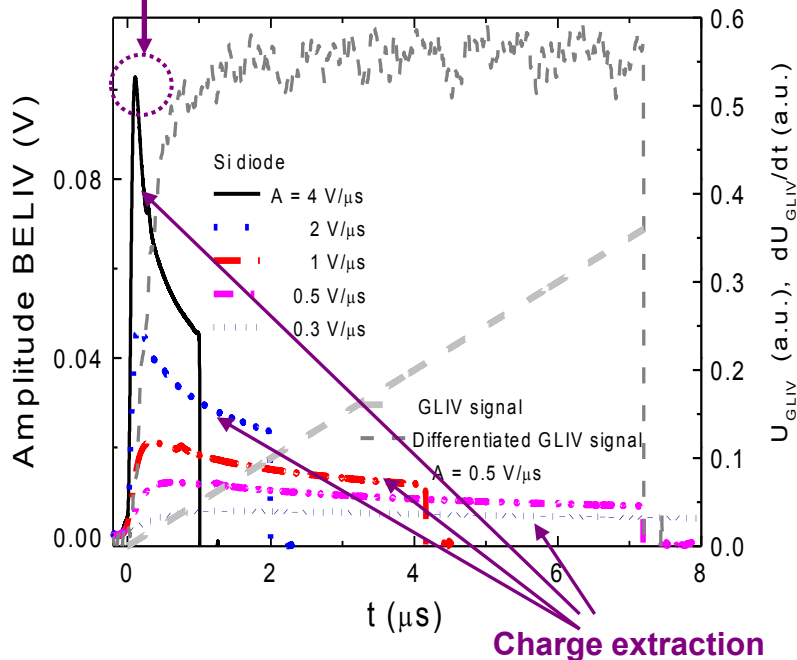


$$i_{R\Sigma}(t) = i_C(t) + i_{diff}(t) + i_g(t) = AC_{b0} \frac{1 + \frac{At}{2U_{bi}}}{\left(1 + \frac{At}{U_{bi}}\right)^{3/2}} + i_{diff\infty} \left(1 - e^{-\frac{eAt}{k_B T}}\right) + \frac{en_i S w_0}{\tau_g} \left(1 + \frac{At}{U_{bi}}\right)^{1/2}$$

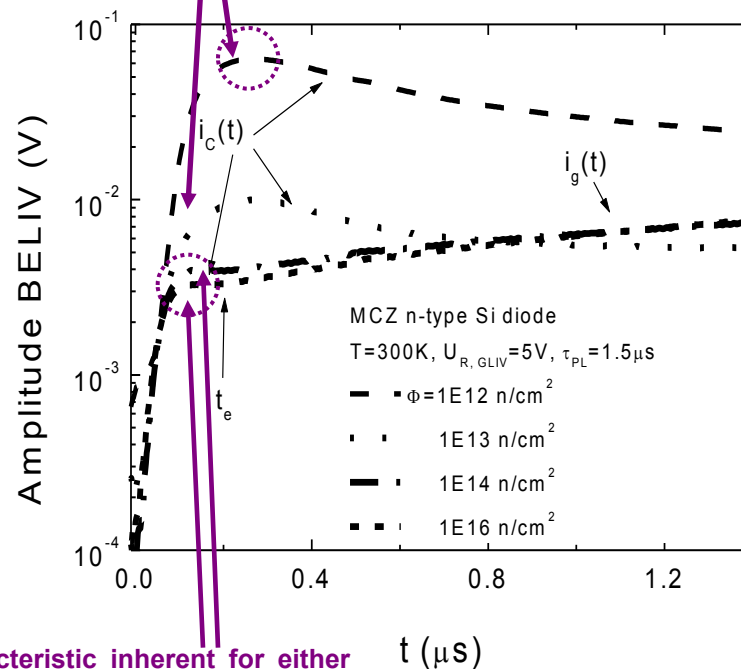
$$t_e = \frac{U_{bi}}{A i_g(0)} \left[\frac{i_C(0)}{4} - i_g(0) + \sqrt{\left(\frac{i_C(0)}{4}\right)^2 + \frac{3}{2} i_C(0) i_g(0)} \right]$$

BELIV transients – qualitative variations of the transient shape

Barrier capacitance



Diode-like characteristic



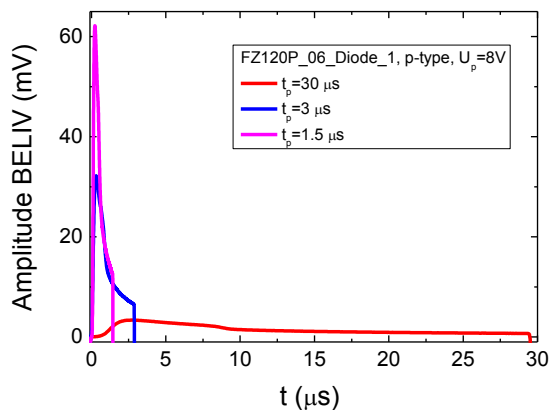
Characteristic inherent for either a capacitor or a diode with very short carrier capture lifetime

Barrier evaluation by linearly increasing voltage (BELIV) technique based on charge extraction current transients measured in the non-irradiated and irradiated with small fluence pin diode at reverse (U_R) biasing by LIV pulses.

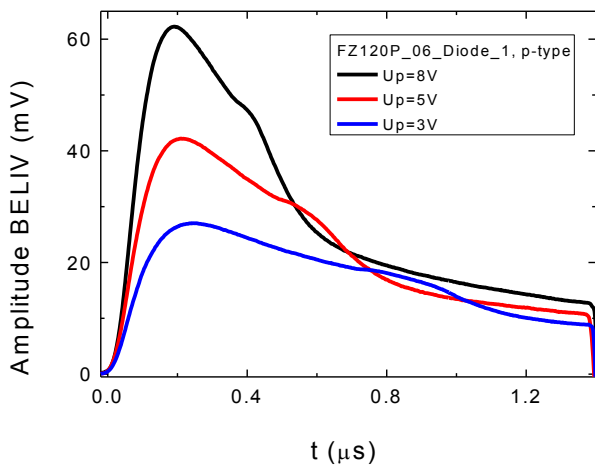
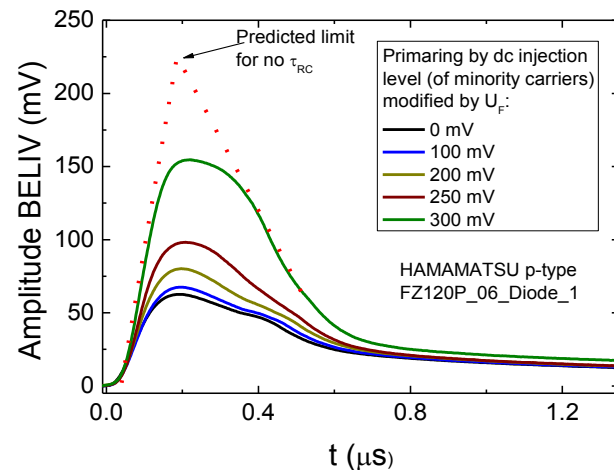
Variations of BELIV transients with irradiation fluence for reverse biased Si pin pad-detector at the same LIV parameters ($A=3 \text{ MV}/\text{s}$, $\tau_{\text{PL}}=1.5 \mu\text{s}$).

BELIV transients – non-irradiated Hamamatsu diodes (T=300 K)

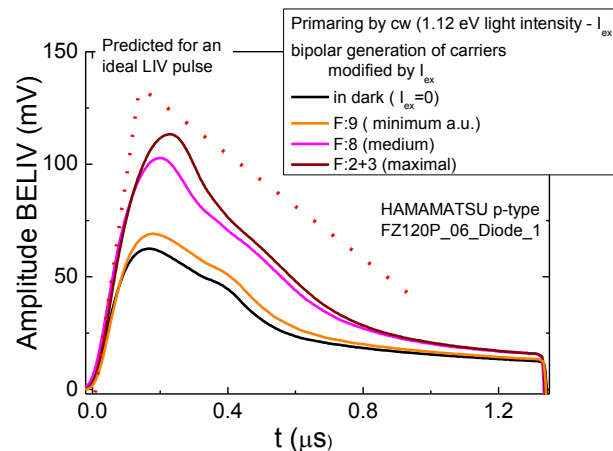
in-dark



Primary steady-state filling of traps by dc injection (U_F) and cw bias-illumination

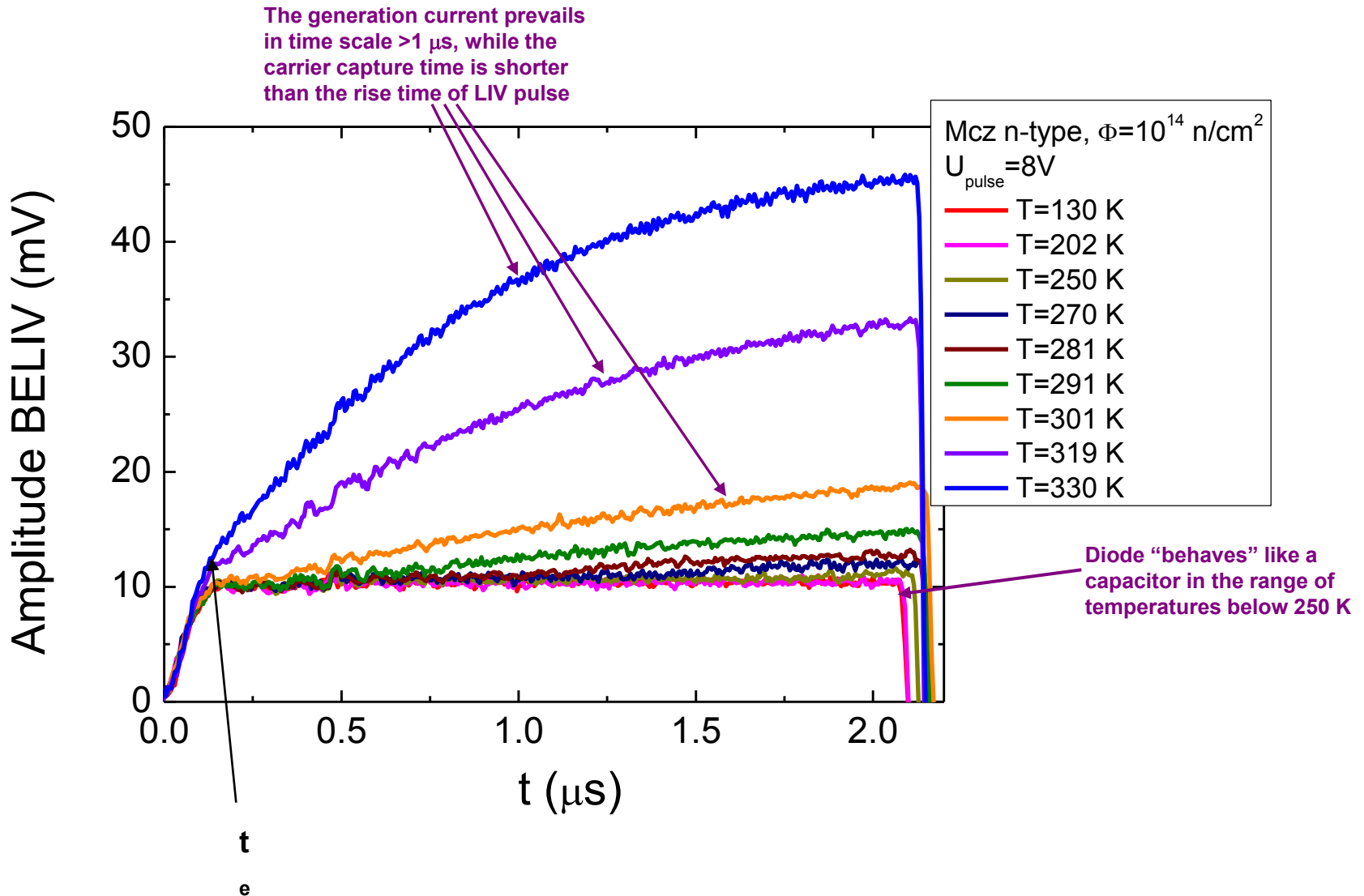


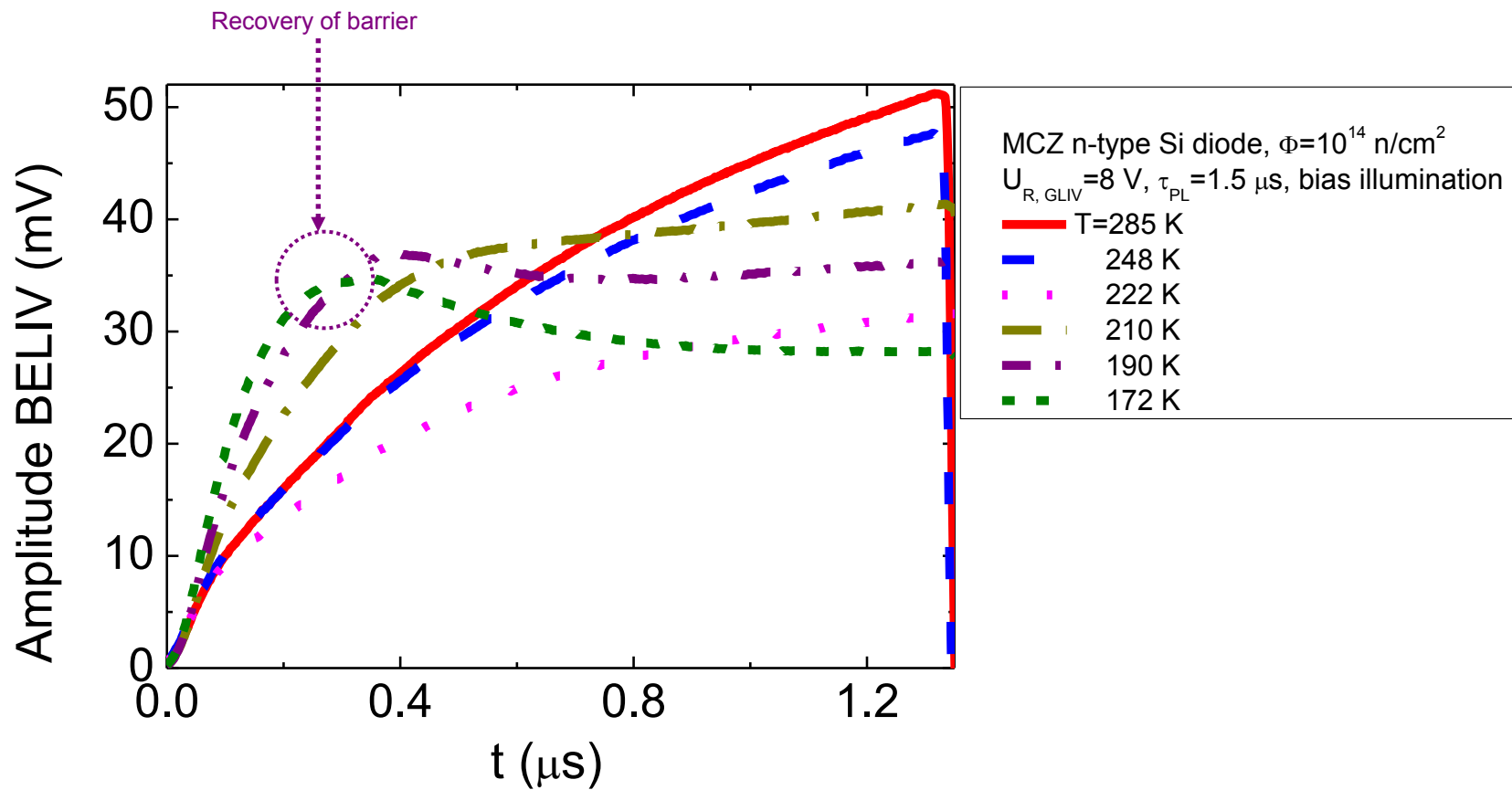
Improvement of barrier (relatively to a black transient on left Fig.) by steady-state filling of traps



Modification of BELIV transients caused by fast trap primary filling in pin diodes containing p-type base by exploiting either dc U_F injection of minority carriers or bipolar injection of carriers by cw IR light additional illumination

Temperature dependent BELIV transients – in neutron 10^{14} cm^{-2} irradiated MCZ diode





Suppression of traps (by combined cooling and primary filling) and recovery of barrier can be implemented by varying the external factors of temperature and of fixed bias cw illumination



TCT (transient current technique)- ChCT(charge collection transient technique)
-TOF (time of flight)

ChCT signal transforms to TCT signal with reduction of excitation I_{ex} density (when $n_{ex} \rightarrow n_{tr}$) in non-irradiated MCZ Si samples

$$n_{tr} = \varepsilon \varepsilon_0 U / e d^2, \quad w \rightarrow d = f(U), \quad n_{ex} = (1-R) \alpha (1 - e^{-\alpha d}) I_{ex} \approx (1-R) \alpha I_{ex} |_{\alpha d \gg 1}$$

TCT signal transforms to TOF signal with enhancement of fluence (when $t_{tr} \ll \tau_M$, or $t_{tr} \rightarrow \tau_M$, $\tau_R \ll \tau_M$) in the irradiated ($\Phi > 10^{13} \text{ cm}^{-2}$) samples

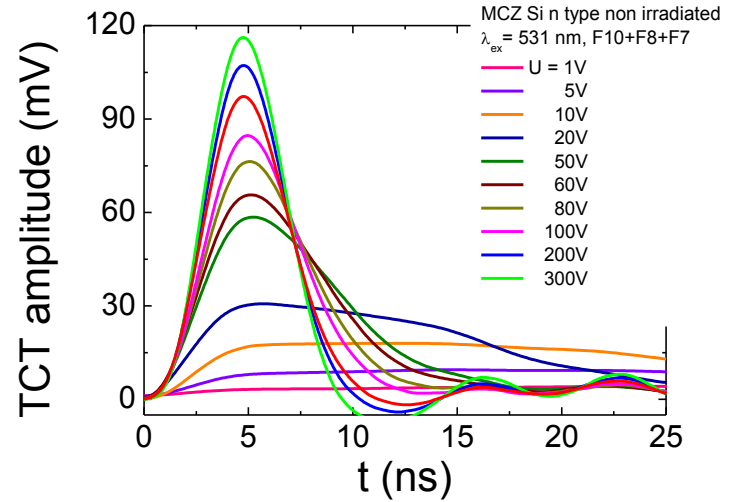
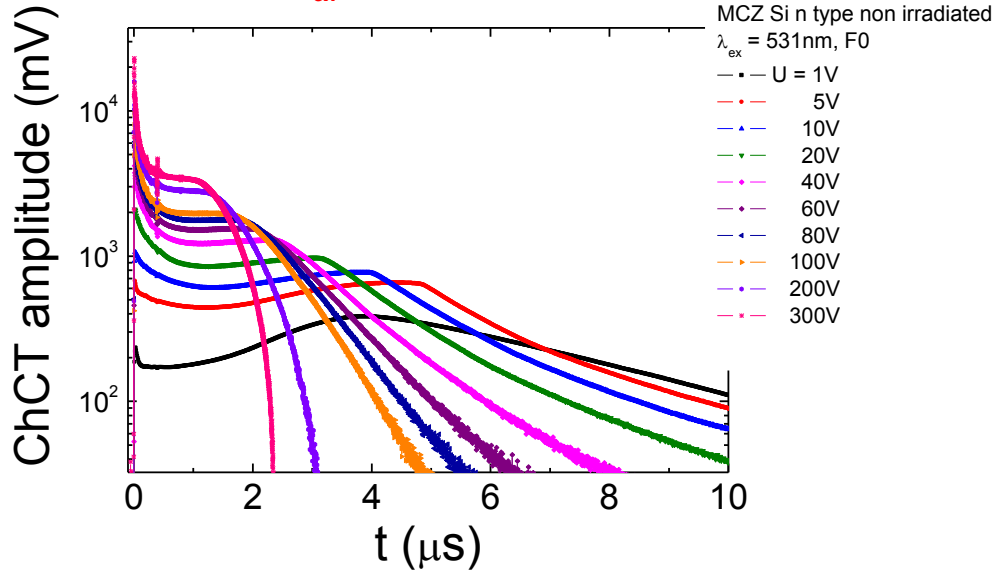
$$\tau_{tr} = d^2 / \mu U, \quad \tau_M = \varepsilon \varepsilon_0 / e \mu N_{eff} |_{N_{eff} \rightarrow ni \text{ or } 0}$$



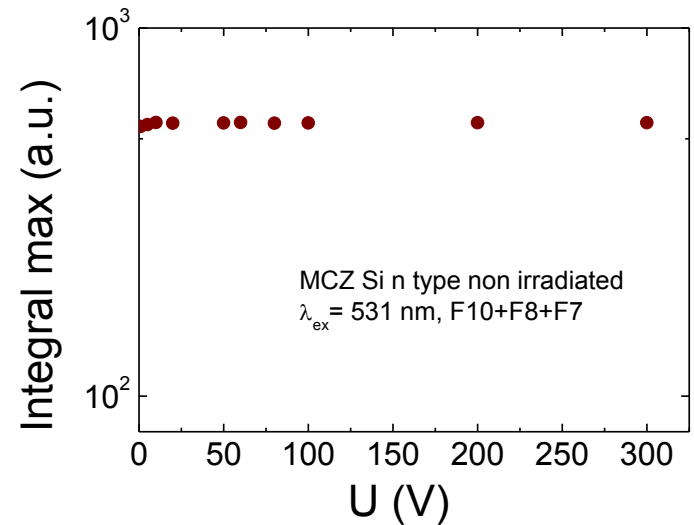
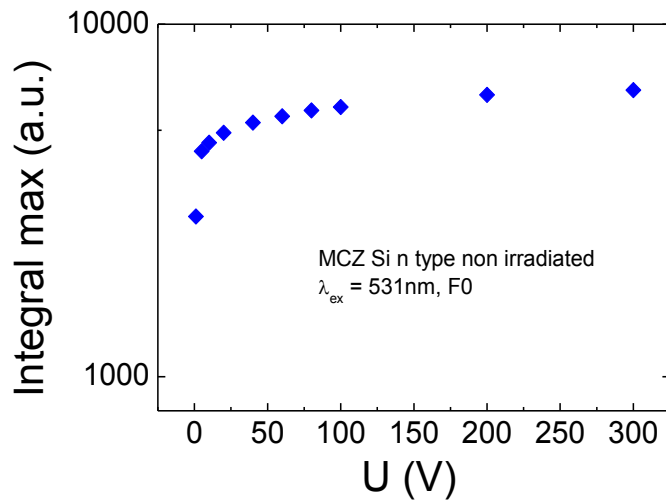
ChCT – TCT in the non-irradiated MCZ Si diode ($d=300 \mu\text{m}$), $\lambda_{\text{ex}}=531 \text{ nm}$, drift of electrons to the back electrode, U_R

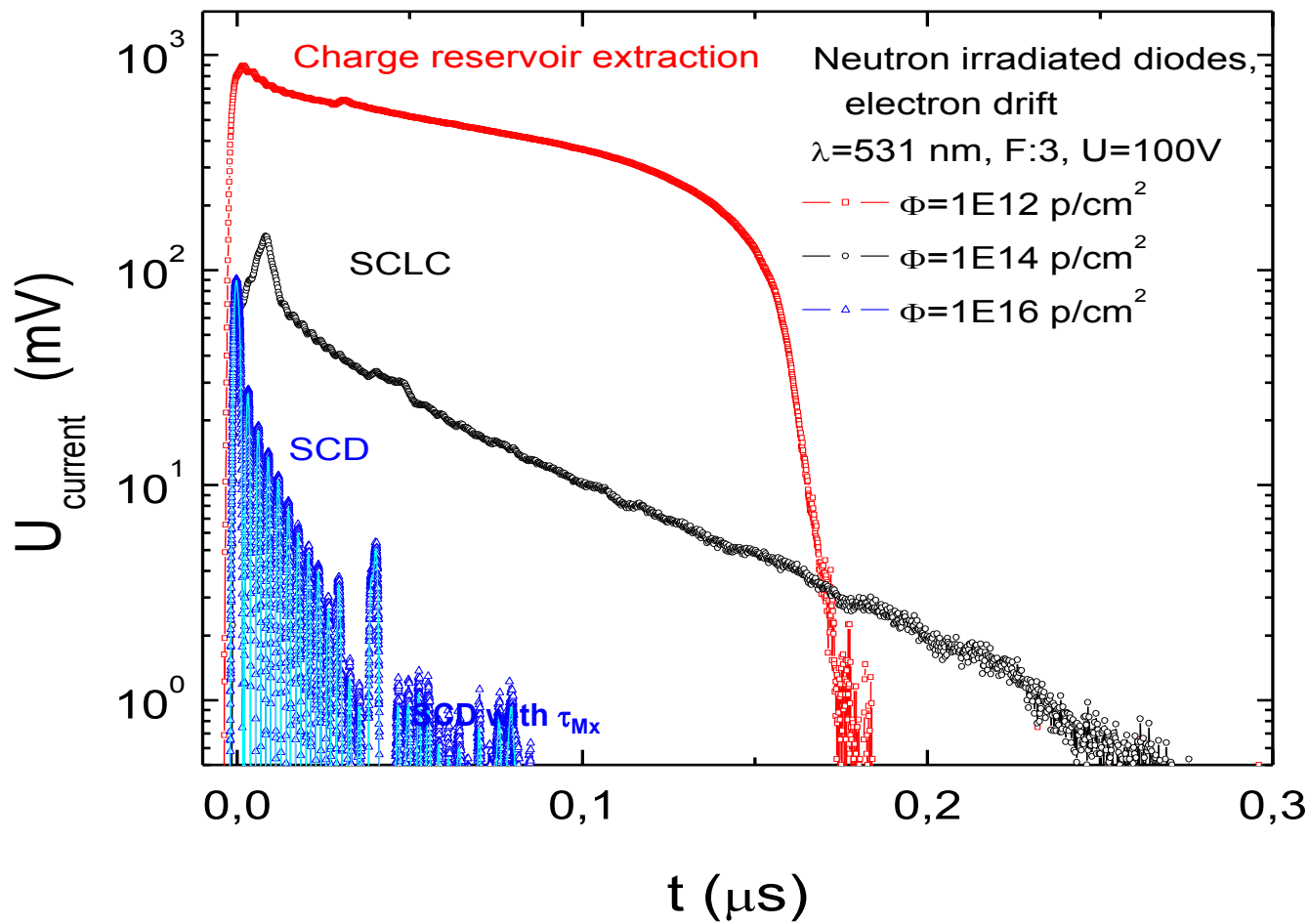
$I_{\text{ex}} = 900 \text{ nJ/pulse}$

$I_{\text{ex}} = 2.5 \text{ pJ/pulse}$



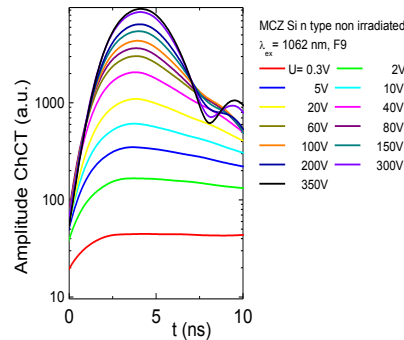
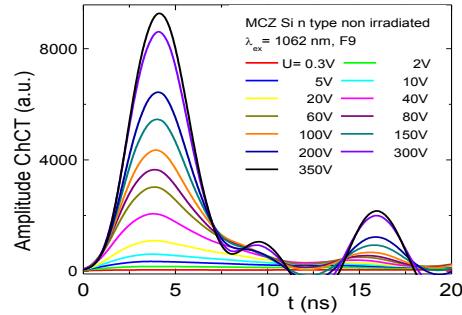
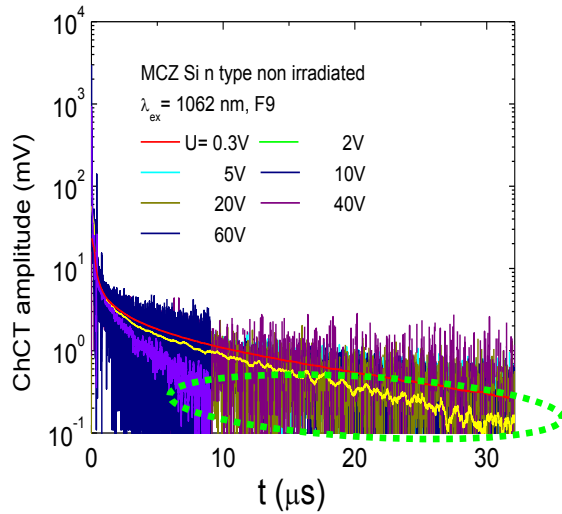
CCE



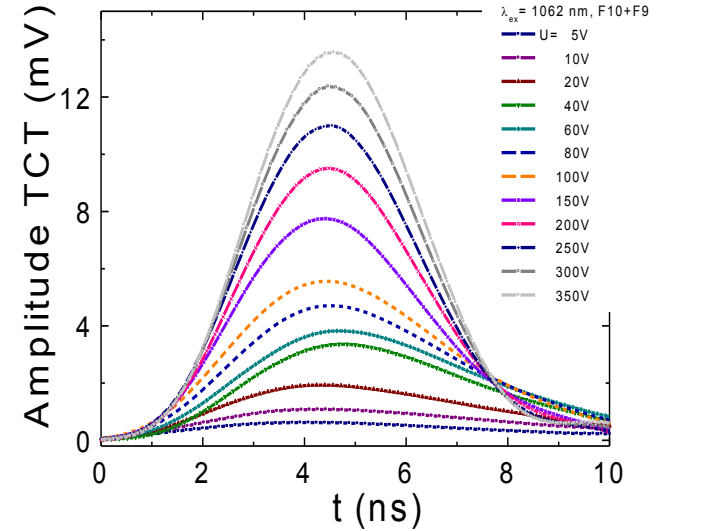


ChCT – TCT in the non-irradiated MCZ Si diode ($d=300 \mu\text{m}$), $\lambda_{\text{ex}}=1062 \text{ nm}$, drift of both type carriers to the opposite electrodes, U_R

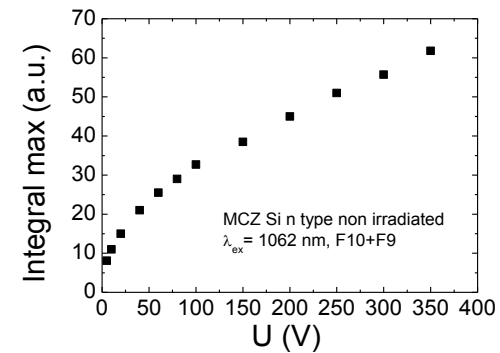
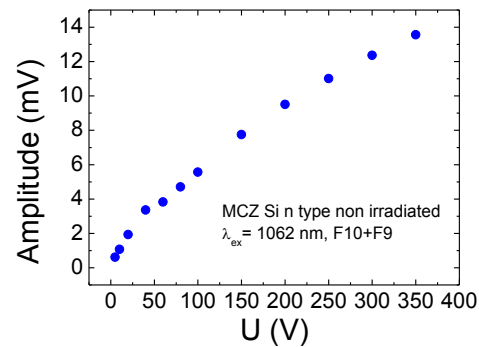
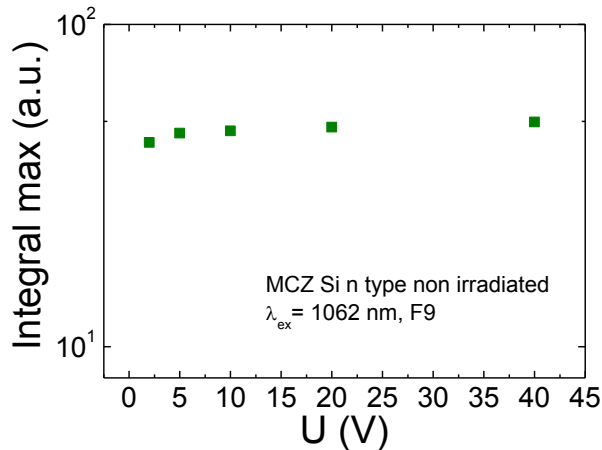
$I_{\text{ex}} = 2 \mu\text{J/pulse}$



$I_{\text{ex}} = 5 \text{ pJ/pulse}$



CCE

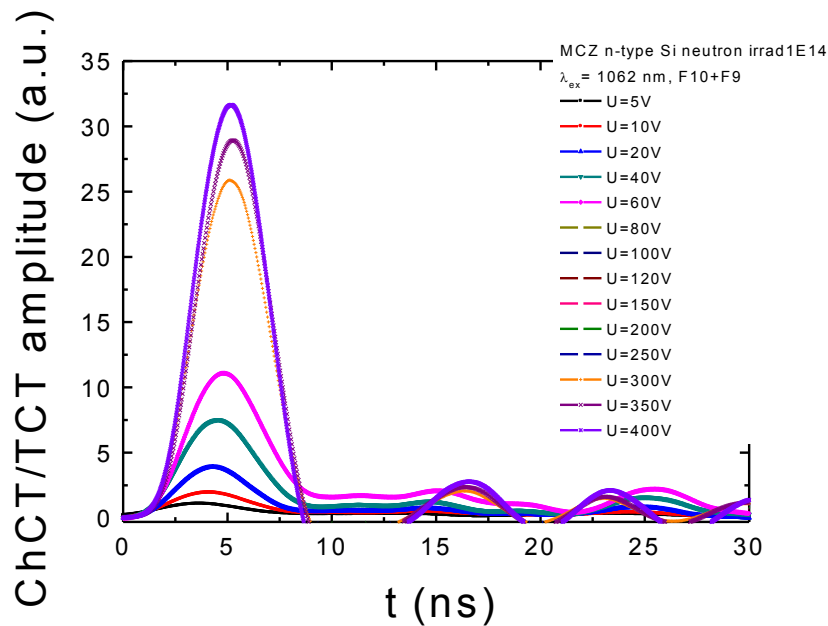


Integral nearly follows the amplitude of a drift signal, a difference due to hidden, long tail of the decay (non-recordable)

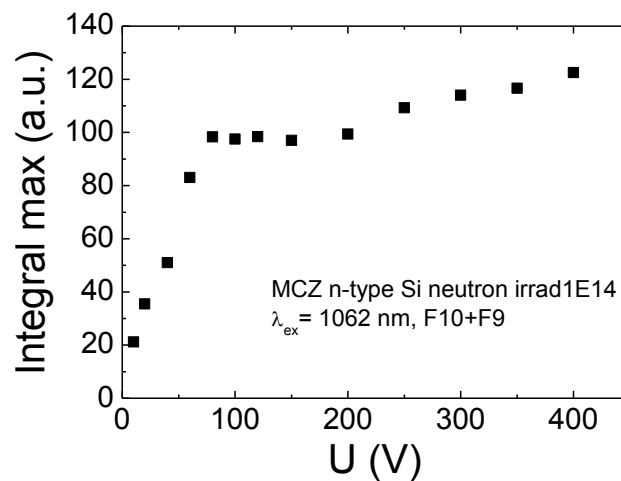
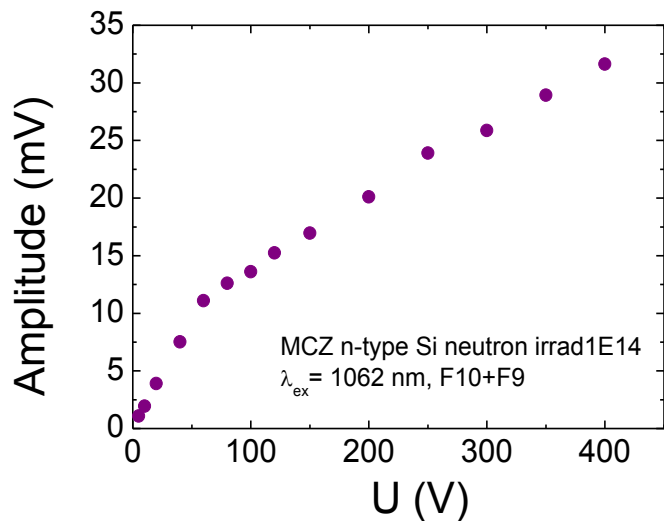


ChCT – TCT in the 10^{14} n/cm² irradiated MCZ Si diode, $\lambda_{ex}=1062$ nm, drift of both type carriers to the opposite electrodes, U_R

$I_{ex}=5$ pJ/pulse

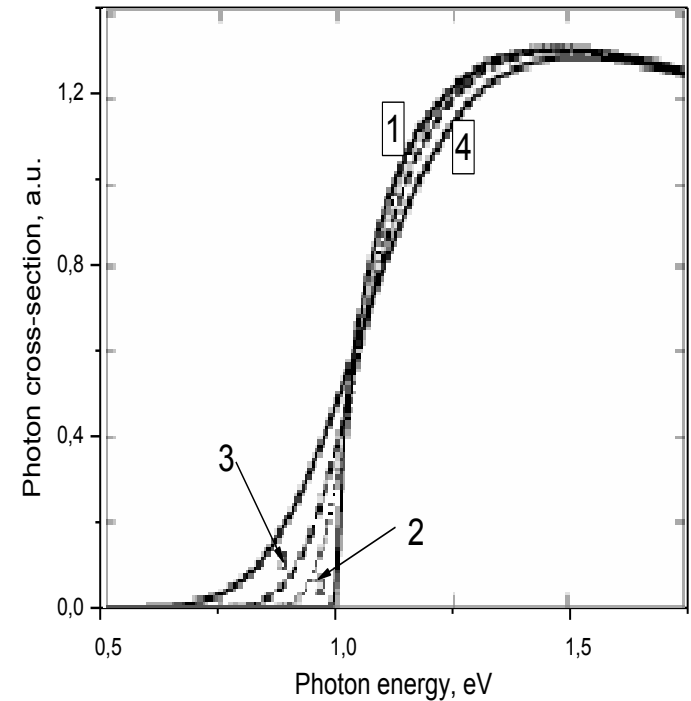


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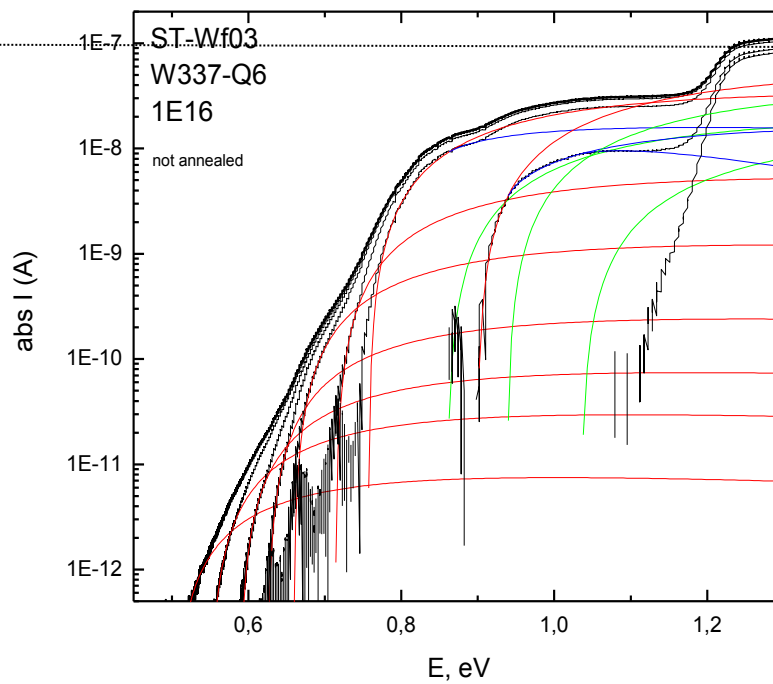
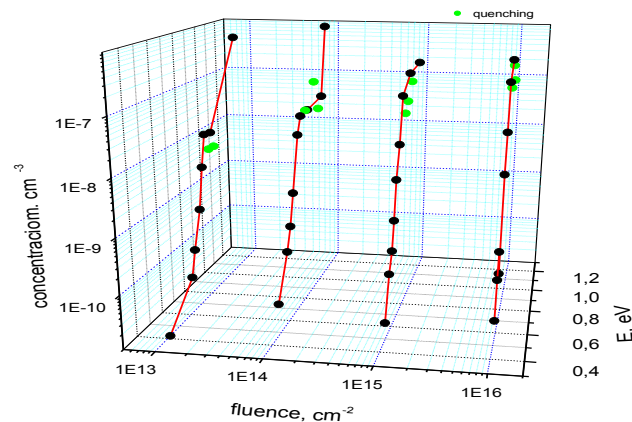
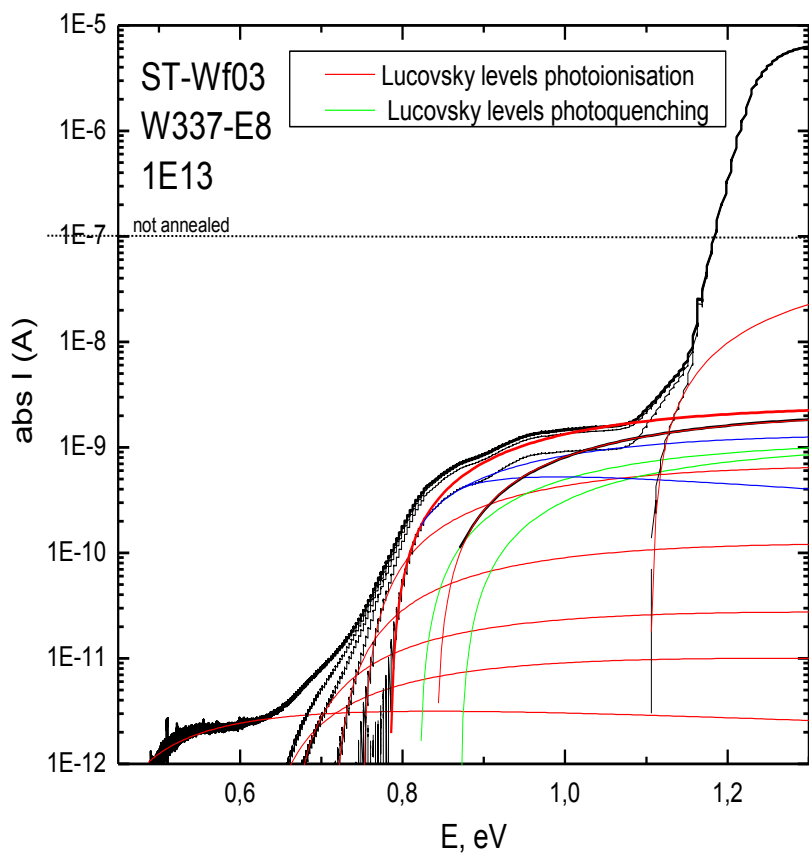


Extrinsic photoconductivity

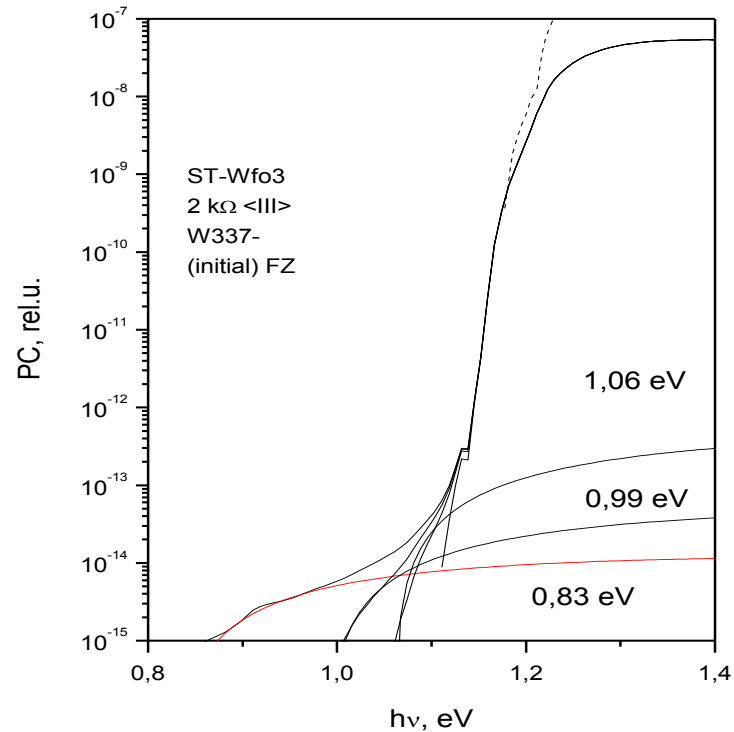
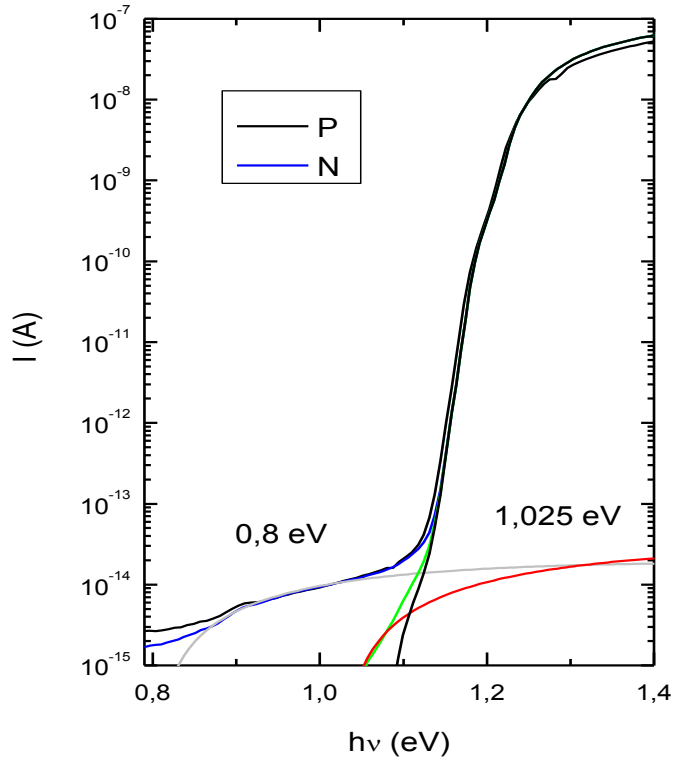
- Lukovsky model was used for the data analyze.
$$I \sim m \times \Delta E_M^{0,5} (h\nu - \Delta E_M)^{1,5} / (h\nu)^3$$
- This model (at low temperatures) does not valid:
 - for the hydrogen type defect and
 - for the inter-deep level state transitions
- Low temperature requires the attention on the filling of the traps and to avoid the influence of electron-phonon coupling



Irradiated Si (Wodean samples)



PC spectra in nonirradiated a new (Hamamatsu) and "old" (Wodean) samples



The deep levels in n- and p- base are lower the Fermi level, i.e., they are in the lower part of the bandgap



A summary:

The initial data of a new series of samples obtained.

The next step: a test of irradiated sample.

Some strange peculiarities observed.

THANK YOU FOR YOUR
ATTENTION!

